ABSTRACT

Plasma & RF Fundamentals

MODULE 104

Learning Activities	Time in Class	Outside Time
6	6 hrs	1 hr

OVERVIEW

One third of modern semiconductor process steps and a variety of other applications employ plasma technology. RF Entergy is commonly used to generate and maintain a plasma which accelerates chemical processes or provides other desired outcomes such as light emission. This module is the first in a series that builds a knowledge foundation for understanding plasma technology and RF energy. Concepts and principles covered include particle behavior under plasma conditions, changes in electromagnetic wave forms, and related variables that affect RF/plasma applications.

MODULE CONTENTS

MARICOPA COMMUNITY COLLEGES

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